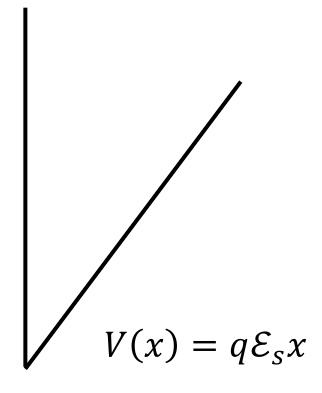
VLSI Devices Lecture 25

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Triangular potential approximation

- Parabolic potential profile
 - However, it is further approximated as a linear potential. →
 Triangular potential well
 - Then, the Schrödinger equation reads

$$\left[-\frac{\hbar^2}{2m_{xx}} \frac{d^2}{dx^2} + q\mathcal{E}_s x \right] \psi(x) = E\psi(x)$$



Its solution

Airy function

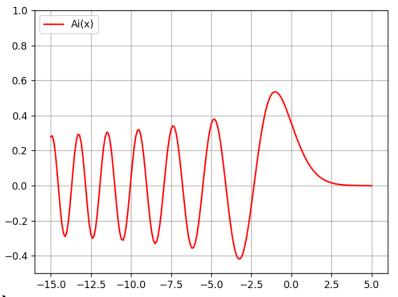
$$Ai(x) = \frac{1}{\pi} \int_0^\infty \cos\left(\frac{t^3}{3} + xt\right) dt \int_{-0.2}^{0.2} dt$$

- Its seond derivative is

$$\frac{d^2}{dx^2}Ai(x) = -\frac{1}{\pi} \int_0^\infty t^2 \cos\left(\frac{t^3}{3} + xt\right) dt$$

- -Note that $\frac{d}{dt}\sin\left(\frac{t^3}{3} + xt\right) = (t^2 + x)\cos\left(\frac{t^3}{3} + xt\right)$.
- -Therefore,

$$-xAi(x) + \frac{d^2}{dx^2}Ai(x) = -\frac{1}{\pi} \int_0^{\infty} \frac{d}{dt} \sin\left(\frac{t^3}{3} + xt\right) dt = 0$$



Simple manipulation

$$\frac{2m_{\chi\chi}}{\hbar^2}q\mathcal{E}_s$$

The Schrödinger equation is written as

$$\left[\frac{d^2}{dx^2} - \frac{2m_{xx}}{\hbar^2}(q\mathcal{E}_S x - E)\right]\psi = \left[\frac{d^2}{dx^2} - \alpha^3\left(x - \frac{1}{q\mathcal{E}_S}E\right)\right]\psi = 0$$

– With a new variable, $\xi=\alpha\left(x-\frac{1}{q\varepsilon_s}E\right)$, it becomes $\left[\frac{d^2}{d\xi^2}-\xi\right]\psi=0$

$$\left[\frac{d^2}{d\xi^2} - \xi\right] \psi = 0$$

- -The solution is $\psi(x) \sim Ai(\xi) = Ai\left(\alpha\left(x \frac{1}{q\mathcal{E}_s}E\right)\right)$.
- -At x = 0, the wavefunction must vanish:

$$-\alpha \frac{1}{q \mathcal{E}_{S}} E_{j} = a_{j}$$
GIST Lecture

Zeros of the Airy function

$$a_0 \approx -2.3381$$
 $a_1 \approx -4.0879$

Eigenenergy

- Zeros are well approximated as $a_j \approx -\left[\frac{3\pi}{2}\left(j+\frac{3}{4}\right)\right]^{2/3}$.
 - -Then, the eigenenergy becomes

$$E_{j} = \frac{q\mathcal{E}_{s}}{\alpha} \left[\frac{3\pi}{2} \left(j + \frac{3}{4} \right) \right]^{2/3} = \left[\frac{3hq\mathcal{E}_{s}}{4\sqrt{2m_{\chi\chi}}} \left(j + \frac{3}{4} \right) \right]^{2/3}$$
 Taur, Eq. (4.46)

–There are two different $m_{\chi\chi}$ values: 0.91 m_0 (degeneracy of 2, g=2) and 0.19 m_0 (degeneracy of 4 , g'=4)

Total inversion charge per unit area

- For a subband,
 - The number of electrosn per unit area

$$n = \frac{4\pi k_B T}{h^2} g \sqrt{m_y m_z} \ln \left[1 + \exp \frac{E_f - E_{min}}{k_B T} \right]$$
 Taur, Eq. (A12.5)

- Summation over subbands

$$Q_i^{QM} = -\frac{4\pi q k_B T}{h^2} \left(g m_t \sum_j \ln\left(1 + \exp\frac{E_f - E_c' - E_j}{k_B T}\right) + g' \sqrt{m_l m_t} \sum_j \ln\left(1 + \exp\frac{E_f - E_c' - E_{j'}}{k_B T}\right) \right)$$

Bottom of the conduction energy at the interface, $E_c' =$ $E_c(\infty) - q\phi_s$

Taur, Eq. (4.49)

Subthreshold region

- In this case,
 - It is well approximated as

$$\approx -\frac{4\pi q k_B T}{h^2} \left(g m_t \sum_j \exp \frac{-E_j}{k_B T} + g' \sqrt{m_l m_t} \sum_j \exp \frac{-E_{j'}}{k_B T} \right) \exp \frac{E_f - E_c'}{k_B T}$$

- Using $E'_c = E_c(\infty) - q\phi_s$,

$$Q_i^{QM}$$

$$\approx -\frac{4\pi q k_B T n_i^2}{h^2 N_c N_a} \left(g m_t \sum_j \exp \frac{-E_j}{k_B T} + g' \sqrt{m_l m_t} \sum_j \exp \frac{-E_{j'}}{k_B T} \right) \exp \frac{q \phi_s}{k_B T}$$

- (Note that
$$\exp \frac{E_f - E_c(\infty)}{k_B T} = \frac{n_i^2}{N_c N_a}$$
.)

Taur, Eq. (4.50)

Shift of threshold voltage

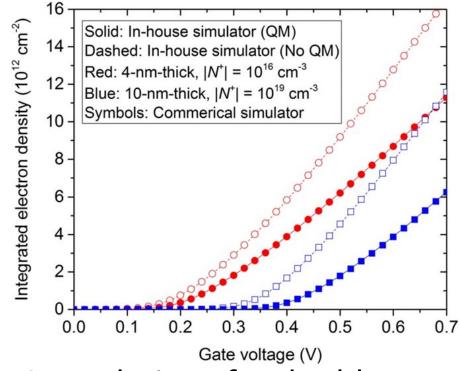
• Q_i^{QM} is smaller than its classical counterpart.

- Additional band bending is required to achieve the same inversion

charge per unit area

– Example taken from our textbook:

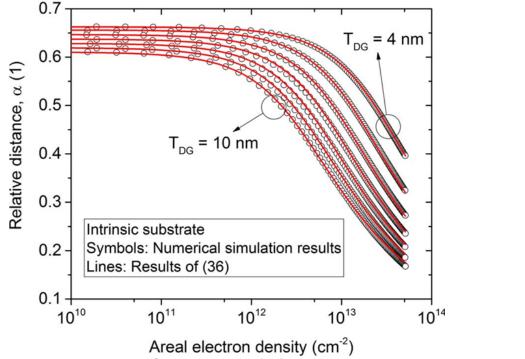
– When N_a is 3 X 10¹⁸ cm⁻³, $\Delta \phi_s^{QM}$ (additional surface potential to match the classical density) is 0.13 V.



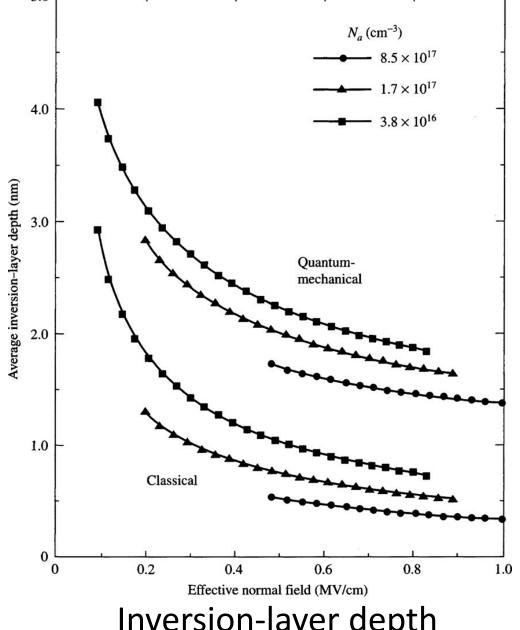
Q-V relations for double-gate MOS structures 8

Inversion-layer depth

- Average distance
 - It reduces at a high gate voltage.
 - However, QM value is larger than CL one.



Average distance for double-gate MOS structures



Inversion-layer depth (Taur, Fig. 4.21) 9

Nanosheet

- It is known that the nanowire is ideal in terms of gate controllability.
 - However, nanosheet transistors are area-efficient.

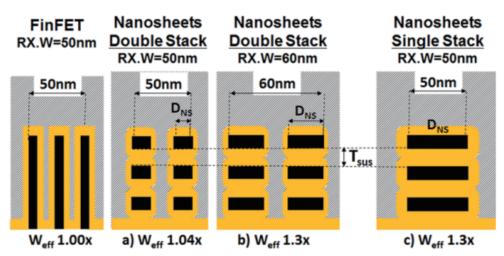


Fig. 2: Increase in Weff going from aggressively scaled FinFET to double and single stack Nanosheets structures. Best improvement is obtained using a single wide Nanosheet stack at constant active width (RX.W).

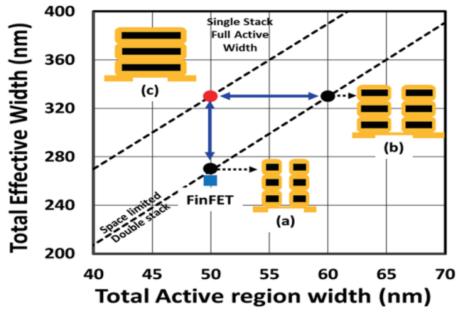


Fig. 3: Improvement in W_{eff} at same footprint going from extremely scaled FinFET to a single wide stack Nanosheet.

Areal efficiency of nanosheet (IBM, VLSI 2017)

Double-gate (DG) MOSFET

- A wide nanosheet can be considered as a double-gate.
 - Two gate contacts
 - The silicon film is usually lightly doped and fully depleted.
 - Performance advantage lies mainly in the ability of DG MOSFETs to scale to a shorter channel length.

Thank you!